

Page 33, line 7, change "Fig. 11 illustrates" to --FIGs. 11(a)-(b) illustrate--.

Page 39, line 5, change "Fig. 13 shows" to --FIGs. 12(a)-(b) show--.

Page 41, line 18, change "comprises" to --may consist of--.

IN THE CLAIMS:

1. (Amended) A micromachine comprising:

a first microstructured portion; and

a second microstructured portion of a predetermined shape, at least a part of

which is formed by mold transfer[, and a], the second microstructured portion being driven

by the first microstructured portion [for driving this second microstructured portion].

2. (Amended) The micromachine according to claim 1, [wherein] said second

microstructured portion [has] having a switching function.

3. (Amended) The micromachine according to claim 1, [wherein] said second

microstructured portion [has a function to be performed] performing as an optical switching element.

4. (Amended) The micromachine according to claim 1, [wherein] said first

microstructured portion and said second microstructured portion [are] being arranged in an array.

5. (Amended) The micromachine according to claim 1, [which] further

[comprises] comprising:

a third microstructured portion of a predetermined shape[, wherein said third microstructured portion is] not driven by said first microstructured portion, [and wherein] at least a part of said third microstructured portion which relates to said second microstructured portion [is] being formed by mold transfer.

6. (Amended) The micromachine according to claim 5, [wherein] one of a predetermined gap [or] and a predetermined step [is] being provided between said second microstructured portion and said third microstructured portion.

7. (Amended) The micromachine according to claim 1, [wherein] said first microstructured portion [is] being formed by photolithography techniques.

8. (Amended) The micromachine according to claim 1, [wherein] said second microstructured portion [is made of] comprising a resin.

9. (Amended) The micromachine according to claim 8, [wherein] said second microstructured portion [is made of] comprising a photosetting resin.

10. (Amended) The micromachine according to claim 8, [wherein] a boundary surface between said first microstructured portion and said second microstructured portion [is made of] comprising a metallic material.

11. (Amended) A micromachine manufacturing method for manufacturing a micromachine, in which a first microstructured portion is operative to drive a second microstructured portion of a predetermined shape, the method comprising:

a first microstructured portion providing step of providing a first microstructured portion; and

a molding step of forming at least a part of said second microstructured portion[, which is overlaid] on said first microstructured portion by mold transfer, after said first microstructured portion is [manufactured] provided.

12. (Amended) The micromachine manufacturing method according to claim 11, [wherein] said second microstructured portion [has] having a switching function.

13. (Amended) The micromachine manufacturing method according to claim 11, [wherein] said second microstructured portion [has a function to be performed] performing as an optical switching element.

14. (Amended) The micromachine manufacturing method according to claim 11, further comprising a plurality of first microstructured portions and a plurality of second microstructured portions [wherein said first microstructured portion and said second microstructured portion are] arranged in an array, [and wherein] a part of each of the plurality of second microstructured portions arranged in the array [is] being transferred using a same mold used in said molding step.

15. (Amended) The micromachine manufacturing method according to claim 11, [wherein] said micromachine [has] comprising a third microstructured portion[, which is] not driven by said first microstructured portion, [and wherein] at least a part of said third microstructured portion which relates to said second microstructured portion [is] being transferred using a same mold used in said molding step.

16. (Amended) The micromachine manufacturing method according to claim 15, [wherein] one of a predetermined gap [or] and a predetermined step [is] being formed between said second microstructured portion and said third microstructured portion in said molding step.

17. (Amended) The micromachine manufacturing method according to claim 11, [which] further [comprises] comprising:

a photolithography step [to be] performed before said molding step, [wherein] said first microstructured portion [is] being formed by photolithography techniques in said photolithography step.

18. (Amended) The micromachine manufacturing method according to claim 17, [which] further [comprises] comprising:

[a] an etching step of etching a sacrifice layer after said molding step,

A2 [wherein] said sacrifice layer, which is provided around said first microstructured portion, [is]   
 Could not being etched at said photolithography step.

19. (Amended) The micromachine manufacturing method according to claim 17, [wherein] no metallic film [is] being formed on a boundary surface, on which said second microstructured portion is stacked, in said photolithography step.

20. (Amended) The micromachine manufacturing method according to claim 11, [which] further [comprises] comprising:

a sacrifice layer providing step of providing a sacrifice layer around said first microstructured portion before said molding step.

21. (Amended) The micromachine manufacturing method according to claim 11, [which] further [comprises] comprising:

a planarizing step of planarizing said first microstructured portion and surroundings thereof before said molding step.

22. (Amended) The micromachine manufacturing method according to claim 11, [wherein] a mold used in said molding step [is] being formed on a silicon substrate by a combination of anisotropic etching and isotropic etching in such a manner so as to have a predetermined shape.

23. (Amended) The micromachine manufacturing method according to claim 11, [wherein] a mold used in said molding step [is] being adapted to transmit light.